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LIST OF PRIOR ART
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Applicant(s): Buschbeck, et al

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U.S. PATENT DOCUMENTS

EI*		Document Number	Date	Name	Class	Subclass	Date Filed
M>	AA	5,755,938	05/26/98	Fukui, et al	—	—	—
M>	AB	5,906,680	05/25/99	Meyerson	—	—	—
M>	AC	6,013,134	01/11/00	Chu, et al	—	—	—
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translated	
							YES	NO
M>	AL	0 463 863 A1	01/02/92	Europe	—	—	X	
M>	AM	11297705	10/29/99	Japan (Abstract)	—	—	X	
M>	AN	2001102314	04/13/01	Japan (Abstract)	—	—	X	
	AO							
	AP							

OTHER PRIOR ART (including Author, Title, Date, Pertinent Pages, etc.)

M>	AQ	Interface Engineering in Silicon ... Cluster Tool, Hendriks, Microelectronic Engineering 25, 1994, Pgs. 185-200					
M>	AR	Cold Walled UHV/CVD ... Layers, Thomsen, et al, Thin Solid Films 294, 1997, Pgs. 72-75					
M>	AS	Atomic Layer Deposition ... Surface Reactors, Klaus, et al, Surface Review and Letters, Vol. 6, Nos. 3 & 4, 1999, Pgs. 435-448					
	AT						

Examiner: *M. A. Sy*

Date Considered: 4/2/2003

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.